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13.12.1996 (72)Inventor: NAKATSUJI TADAO

(71)Applicant: SAKAI CHEM IND CO LTD

YOSHIDA KIMIHIKO

(54) ADSORBENT FOR SULFUR COMPOUND

(57)Abstract:

PROBLEM TO BE SOLVED: To efficiently adsorb and remove sulfur compds. from odorous gas by depositing at least one kind of element selected from Ce and La on manga nese oxide having a specified or larger specific surface area and a specified diffraction angle at the diffraction peak of the max. intensity in X-ray diffrac tion. SOLUTION: The manganese oxide used has ≥50m2/g specific surface area and 37° ±1° diffraction angle (2 θ) at the diffraction peak of the max. intensity in the X-ray diffraction. The manganese oxide is obtd. by burning a precursor which produces manganese oxide by burning, for example, a manganese salt such as manganese hydroxide while controlling the calcination conditions such as atmosphere, temp. and time. Then at least one kind of element selected from Ce and La is deposited as an active component on the obtd. maganese oxide. Thereby, adsorptivity for sulfur compds. can be synergically increased and duration of adsorptivity for various sulfur compds, can be increased.

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